

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Shigemi OHTSU et al.

Group Art Unit: 1732

Application No.: 10/733,454

Filed: December 12, 2003

Docket No.: 118039

For: PRODUCING METHOD OF POLYMER OPTICAL WAVEGUIDE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of references 1 and 2 is discussed in the present specification.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

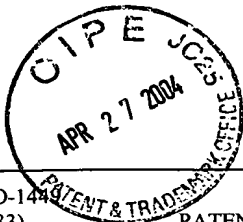
Thomas J. Pardini
Registration No. 30,411

JAO:TJP/mlo

Date: April 27, 2004

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>

Sheet 1 of 1

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118039		APPLICATION NO. 10/733,454	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT(S) Shigemi OHTSU et al.			
				FILING DATE December 12, 2003		GROUP 1732	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	1.	Younan Xia et al.; "Soft Lithography"; Annu. Rev. Mater. Sci.; 1998; Vol. 28; pp 153-184					
	2.	B. Michel et al.; "Printing meets lithography: Soft approaches to high-resolution patterning"; IBM J. RES. & DEV.; Vol. 45, No. 5; September 2001; pp 697-719					
EXAMINER				DATE CONSIDERED			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Date: April 27, 2004